

NIL Industrial Day (June 22-23, 2021) - Program

Virtual Conference

June 22, 2021 ~ NIL Industrial Day



1:00 - 5:30 p.m. CEST

1:00 - 1:10 p.m.

Introduction/Welcome

- | | |
|------------------|--|
| 1:10 - 1:30 p.m. | IMEC (BEL), Eleonora Storace
<i>„NIL at imec: imprint lithography embedded in an advanced lithography Fab ecosystem“</i> |
| 1:30 - 1:50 p.m. | SUSS MicroTec (GER), Simon Drieschner
<i>„Highly efficient beam shaping elements using SMILE imprint technology and Ormocers materials“</i> |
| 1:50 - 2:10 p.m. | SCHOTT (GER), Rüdiger Sprengard
<i>„Glass technology for Augmented Reality, Micro-Optics and Nano-Photonics“</i> |
| 2:10 - 2:30 p.m. | micro resist technology (GER), Mirko Lohse
<i>„NIL and functional materials for the next generation of microfluidics“</i> |
| 2:30 - 2:50 p.m. | Anteryon (NLD), Edwin Wolterink
<i>„Opportunities and challenges in hybrid optics“</i> |
| 2:50 - 3:10 p.m. | DISPELIX (FIN), Ismo Vartiainen
<i>„Diffractive Waveguide Manufacturing @ Dispelix“</i> |

3:10 - 3:30 p.m.

Break

- | | |
|------------------|--|
| 3:30 - 3:50 p.m. | NIL Technology ApS (DNK), Theodor Nielsen
<i>„Nanoimprint of flat optics for consumer electronics and automotive“</i> |
| 3:50 - 4:10 p.m. | EVGroup (AUT), Lisa Vsetecka
<i>„From a Single Die to Wafer Level Production by Step and Repeat Mastering“</i> |
| 4:10 - 4:30 p.m. | GenSpeed Biotech (AUT), Max Sonnleitner
<i>„Roll2Roll manufacturing of microfluidics based Point of Care tests using Nano imprint lithography“</i> |
| 4:30 - 4:50 p.m. | Smart Material Solutions (USA), Nichole Cates
<i>„Scalable fabrication of large-area plasmonic devices“</i> |
| 4:50 - 5:10 p.m. | Facebook Reality Labs (USA), Tingling Rao
<i>„NIL process to mass-manufacture highly-angled HRI gratings for AR combiners“</i> |
| 5:10 - 5:30 p.m. | Leia Inc. (USA), Sonny Vo
<i>„The Power of NanoImprint Lithography to achieve a robust Diffractive Lightfield Back Lighting (DLB™) for interactive holograms“</i> |

5:30 p.m. - open

Online Gathering

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micro resist technology GmbH
Köpenicker Straße 325
12555 Berlin - Germany
www.microresist.com

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6:00 a.m - 2:00 p.m. CEST

6:00 - 8:00 a.m.

Online Gathering

8:00 - 8:10 a.m.

Welcome

- | | |
|-------------------|---|
| 8:10 - 8:30 a.m. | Monash University (AUS), Victor Cadarso Busto
<i>„Next Generation Cell Culture Tools Featuring Micro- and Nanotopographies for Biological Screening“</i> |
| 8:30 - 8:50 a.m. | Moveon (SGP), Teck Lee Chee
<i>„A Method for Sustained & Scalable Fabrication of Diffractive Optics Elements Via Nanoimprint Lithography“</i> |
| 8:50 - 9:10 a.m. | SCIVAX (JPN), Motohiko Tsuchiya
<i>„Coverage of Scivax Business Area“</i> |
| 9:10 - 9:30 a.m. | Korea University (KOR), Heon Lee
<i>„Fabrication of metalens by nanoimprint lithography“</i> |
| 9:30 - 9:50 a.m. | OpTool (SWE), Babak Heidari
<i>„Polymer stamp materials for imprint lithography applications“</i> |
| 9:50 - 10:10 a.m. | GermanLitho (CHN), Ran Ji
<i>„Nanoimprint total solution for AR waveguide mass production“</i> |

10:10 - 10:30 a.m.

Break

- | | |
|--------------------|---|
| 10:30 - 10:50 a.m. | AMO (GER), Max Lemme
<i>„European Experimental Pilot Line for 2-dimensional Materials“</i> |
| 10:50 - 11:10 a.m. | Morphotonics (NLD), Pim Veldhuizen
<i>„How to ‘democratize’ Large Area Nanoimprinting for the masses via Roll-to-Plate Technology“</i> |
| 11:10 - 11:30 a.m. | SÜSS MicroOptics (CHE), Patrick Heissler
<i>„Microlens Imprint for Automotive Lighting“</i> |
| 11:30 - 11:50 a.m. | Profactor (AUT), Michael Mühlberger
<i>„Step&repeat UV-Nanoimprinting as a versatile tool in the Nanoimprint process chain“</i> |
| 11:50 - 12:10 a.m. | 5microns (GER), Thomas Handte
<i>„Application possibilities of Soft UV-NIL: From patterning flat and curved surfaces to combinations with bi- and trilayer lift-off processes“</i> |
| 12:10 - 12:30 a.m. | Nanoscribe (GER), Jörg Smolenski
<i>„2-Photon Grayscale Lithography for microoptical mastering and replication“</i> |

12:30 - 12:40 a.m.

Farewell, special announcements

12:40 a.m. - 2:00 p.m.

Online Gathering

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